

Nanoscale

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2 Atomistic simulations of electrochemical metallization cells:
3 mechanisms of ultra-fast resistance switching in nanoscale devices

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7 *We describe a new method that enables reactive molecular dynamics (MD) simulations of*
8 *electrochemical processes and apply to study electrochemical metallization cells (ECMs). The*
9 *model, called EChemDID, extends the charge equilibration method to capture the effect of*
10 *external electrochemical potentials on partial atomic charges and describes its equilibration*
11 *over connected metallic structures, on-the-fly, during the MD simulation. We use EChemDID to*
12 *simulate resistance switching in nanoscale ECMs; these devices consist of an electroactive metal*
13 *separated from an inactive electrode by an insulator and can be reversibly switched to a low-*
14 *resistance state by the electrochemical formation of a conducting filament between electrodes.*
15 *Our structures use Cu as the active electrode and SiO₂ dielectric and have dimensions at the*
16 *foreseen limit of scalability of the technology, with dielectric thickness of approximately 1 nm.*
17 *We explore the effect of device geometry on switching timescales and find that nanowires with*
18 *an electroactive shell, where ions migrate towards a smaller inactive electrode core, result in*
19 *faster switching than planar devices. We observe significant device-to-device variability in*
20 *switching timescales and intermittent switching for these nanoscale devices. To characterize the*
21 *evolution in the electronic structure of the dielectric as dissolved metallic ions switch the device,*
22 *we perform density functional theory calculations on structures obtained from an EChemDID*
23 *MD simulation. These results confirm the appearance of states around the Fermi energy as a*

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24 *metallic filament bridges the electrodes and show that the metallic ions and not defects in the*
25 *dielectric contribute to the majority of those states.*

26

27 1. Introduction

28 Electrochemical processes are at the heart of a wide range of established and emerging
29 applications from energy storage¹ and materials processing to nanoelectronics^{2,3,4,5} and
30 neuromorphic computing.^{6,7} In nominally all applications of current interest the operation of
31 devices is an emergent phenomena that originates from the interplay between processes with
32 disparate time and length scales; these include: electrochemical reactions at complex
33 interfaces, dissolution and deposition of ions, their transport and aggregation, injection and
34 trapping of electrons and holes, changes in composition, phase and valence change in the
35 electrolytes, Joule heating and electromigration. Remarkably, some of these devices can be
36 scaled down to the nanoscale and operate at nanosecond timescales,⁸ opening exciting
37 potential applications but also complicating their experimental characterization. As a result, the
38 atomistic mechanisms that govern the operation of devices like batteries, pseudocapacitors and
39 electrochemical metallization cells are not fully understood. Given these significant challenges
40 and the increasingly important role of molecular dynamics simulations in materials science, it is
41 perhaps surprising that the first attempts to describe electrochemical processes using empirical
42 force field methods date back only a few years.^{9,10,11} In this paper we describe the
43 electrochemistry dynamics with implicit degrees of freedom EChemDID method, that enabled
44 the first fully atomistic simulations of electrochemical metallization cells (ECMs) that can exhibit

45 ultra-fast resistance switching and apply to explore the role of device geometry and atomic
46 processes in the switching of ECMs.

47 Nanoscale resistance switching electrochemical devices hold great promise as memory and
48 logic elements in future nanoelectronics devices with the potential to contribute to the
49 extension of Moore's law beyond the rapidly approaching *end of scaling* and even enable
50 neuromorphic computing. *Resistance-* and *threshold-switching* electrochemical cells are
51 fascinating devices that can reversibly or irreversibly change their electrical resistance with an
52 applied voltage via a variety of processes induced by electrochemistry.^{12,13,14} Their deceptively
53 simple structure, consisting of two metallic electrodes separated by a solid dielectric or
54 electrolyte, seems at odds with the wide range of I-V characteristics that can be achieved by the
55 appropriate choice of materials:¹³ from linear to non-linear bipolar and nonpolar resistance
56 switching to threshold switching (an abrupt but reversible change in resistance). Importantly
57 both from applied and basic science points of view, these devices can exhibit switching in
58 nanosecond timescales⁸ and scaling to approximately ten nanometers,¹⁵ where the distinction
59 between material and device becomes meaningless. Despite the significant experimental and
60 theoretical efforts devoted to these devices in recent years the underlying materials processes
61 responsible for their remarkable properties are not fully known. Even the switching
62 mechanisms, interfacial reactions, and the nature of the conducting paths are not known in
63 many cases.¹³ Recent experimental studies based on high-resolution transmission electron
64 microscopy imaging¹⁶ and scanning tunneling microscopy^{17,18} are providing key insight and
65 quantitative information regarding the fundamental physics of these devices. However, these
66 techniques are not without limitations, especially when dealing with devices at their

67 miniaturization limit (few nanometers) and operating at ultra-fast speeds (nanoseconds). In
68 Section 3 of this paper we use EChemDID to explore the resistive switching of nanoscale ECMs
69 consisting of Cu as the active electrode and SiO₂ dielectrics. We focus on the effect of device
70 geometry on switching dynamics and find that nanowire geometry tends to facilitate the
71 creation of metallic filament. Interestingly, the simulations show that switching occurs with
72 negligible changes in the atomic structure of the amorphous dielectric. Section 4 introduces
73 multiscale simulations coupling EChemDID to ab initio electronic structure calculations to study
74 the electrical characteristics of the systems. We find an increased number of states around the
75 Fermi energy of the dielectric as a metallic filament bridges the electrodes and that these states
76 are predominantly originate on the metallic ions and not on defects in the dielectric.

77 2. Reactive molecular dynamics of electrochemistry

78 2.1 Reactive MD simulations

79 The use of many-body, partial bond-orders to describe covalent interactions^{19,20} together with
80 charge equilibration methods (QEq, initially proposed by Rappe and Goddard²¹ and by Mortier
81 at al.²²) to obtain geometry dependent partial atomic charges led to the development of
82 powerful reactive force field such as ReaxFF,²³ COMB²⁴ and REBO²⁵. These reactive potentials
83 enable large-scale (multi-million atoms) molecular dynamics of materials processes involving
84 chemistry. Examples of recent successes include areas as disparate as shock-induced
85 decomposition of explosives,²⁶ combustion,²⁷ water reactions in cement,²⁸ and reactions in
86 nanomaterials.²⁹ In this paper we use the reactive force field ReaxFF that has been
87 parameterized to describe Cu, SiO₂ and its interactions^{30,31} to model the ECMs of interest. A
88 detailed description of the potential including extensive validation tests and sensitivity analysis

89 are included in the Supporting Information of Ref. [10] and will not be repeated here. The
 90 following subsection describes how EChemDID enhances reactive MD simulations enabling the
 91 description of an external electrochemical potentials to reactive metallic electrodes.

92 2.2 EChemDID simulations

93 Over the last 10 years Strachan and collaborators developed a family of simulation techniques
 94 denoted dynamics with implicit degrees of freedom (DID)³² that was recently extended to
 95 describe electrochemistry. DID couples particle dynamics with the evolution of degrees of
 96 freedom that are not captured explicitly in the particle description. For example, an important
 97 application of DID is the capability of describing the thermal role of electrons in MD simulations
 98 of metals via an implementation of the two-temperature model.³³

99 DID describes time evolution of the local electronic temperature in the vicinity of atom i (T_i^{ele})
 100 using the atoms as a grid and coupling to the atomistic dynamics via the position update
 101 equation:³³

$$102 \quad \dot{R}_i = V_i + \gamma_i F_i \quad (1a)$$

$$103 \quad \dot{V}_i = \frac{F_i}{M_i} \quad (1b)$$

$$104 \quad \dot{E}_i^{ele} = C_i \dot{T}_i^{ele} = \gamma |F_i|^2 + \kappa^{ele} \nabla^2 T_i^{ele} \quad (1c)$$

105 where the subscripts denote atoms, R, V, F and M are atomic position, velocity, force and mass,
 106 and κ^{ele} is the thermal conductivity of the valence electrons. The dynamical parameter γ_i
 107 governs the strength and directionality of the energy transfer between the electronic and
 108 atomic subsystems at location i . It is defined as: $\gamma_i \propto \mu(T_i^{ion} - T_i^{ele})$ where T_i^{ion} is the local

109 atomic temperature in the vicinity of atom i and μ is the strength of the electron-phonon
110 coupling. The Laplacian in equation (1c) is solved numerically via:^{32,33}

$$111 \quad \nabla^2 T_i^{ele} = \sum_{j \neq i} \frac{T^i - T^j}{R_{ij}^2} \omega(R_{ij}) \quad (2)$$

112 where ω is a localized weighting function that defines the extent of the local neighborhood of
113 the calculation; see Ref. [32] and its supplementary information document. The range of this
114 local weighting function is a few atomic distances and its details do not affect the results in an
115 appreciable manner; this is due to the fact that in the applications of interest the local
116 electronic temperature and its Laplacian do not vary significantly within atomic distances. The
117 DID formulation has several desirable properties, total energy (ions plus electrons) is conserved,
118 the equations are Galilean invariant and we demonstrated the strong foundations of the
119 approach in statistical mechanics.³³ The method was recently extended to accurately describe
120 metal/semiconductor and metal/insulator interfaces by enabling direct electron-phonon
121 coupling across the interface.³⁴

122 We recently combined the DID method with a modified version of charge equilibration to
123 enable the application of external voltages in reactive MD simulations. This new method, called
124 EChemDID, enabled the first atomistic simulation of an electrochemical metallization cell.¹⁰ In
125 the QEq formalism, partial atomic charges are computed on the fly during molecular dynamics
126 simulations from a self-consistent minimization of the total electrostatic energy, written as:^{21,22}

$$127 \quad E(\{R_i\}\{Q_i\}) = \sum_i^N \left(\chi_i Q_i + \frac{1}{2} H_i Q_i^2 \right) + \sum_{i < j}^N Q_i Q_j J(R_{ij}) \quad (3)$$

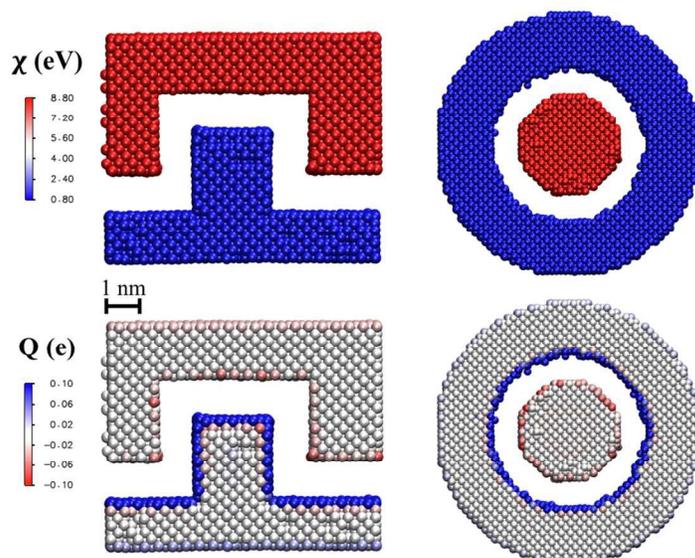
128 where $J(R)$ is the distance dependence of the electrostatic interaction (often shielded
129 Coulomb). QEq requires atomic electronegativity χ_i and hardness H_i parameters as input and is
130 often parameterized against partial charges obtained from *ab initio*. The application of an
131 external electrochemical potential difference $\Delta\phi$ between atoms in two electrodes causes an
132 energy difference in an electron of $e\Delta\phi$; this can be accomplished within QEq by changing the
133 electronegativity in one electrode to $\chi_i \rightarrow \chi_i + \Delta\phi/2$ and to $\chi_i \rightarrow \chi_i - \Delta\phi/2$ in the other. To
134 simulate the effect of an external electrochemical potential EChemDID assigns an additional
135 dynamical variable to each metallic atom to represent the local external electrochemical
136 potential ϕ_i . This value is added to the atomic electronegativity used for charge equilibration,
137 thus affecting the charge distribution and enabling electrochemical processes.

138 The challenge is to dynamically equilibrate the electrochemical potential in connected metallic
139 regions during a reactive simulation, including atoms dissolving into the dielectric or depositing
140 from it. EChemDID describes this equilibration process using a diffusion equation for ϕ_i :

$$141 \quad \dot{\phi}_i = k^\phi \nabla^2 \phi_i, \quad (4)$$

142 where k^ϕ is an effective diffusivity for the electrochemical potential. This fictitious dynamics
143 (instead of solving Maxwell's equations) is chosen for computational convenience. The
144 electrochemical potential propagates at the speed of light and, consequently, its equilibration
145 occurs much faster than any atomistic processes. For our purposes the details of this ultra-fast
146 equilibration are irrelevant and sufficiently fast diffusive equilibration meets our needs. We
147 numerically solve equation (4) on-the-fly during the MD simulation using atoms as a grid and a
148 local weighting function as in the DID method described above, Eq. (3).

149 Figure 1 exemplifies EChemDID in the two devices of interest in this paper: i) a configuration
150 with a fin-shaped active electrode and ii) a core/shell nanowire. The snapshots show the
151 metallic atoms in the systems (the dielectric is not shown for clarity) and atoms are colored by
152 electrochemical potential in the top panels and partial atomic charge in the bottom ones. In
153 these simulations an electrochemical potential difference of 8V is applied to a group of atoms
154 in the active (electropositive, blue) and inactive (negative, red) electrodes far away from the
155 electro-active interfaces. As seen in the top panels, EChemDID equilibrates the applied
156 electrochemical throughout the metallic structures and affects the atomic charges, bottom
157 panels. We see that charges appropriately localize at the free surface of the metallic structures.



158
159 *Figure 1. Atomic structure of the ECM devices studied and the equilibrated local electrochemical*
160 *potential under an applied voltage of 8 V (top) as well as the corresponding partial atomic*
161 *charges (bottom)*

162 An important by-product of EChemDID is its ability to describe resistive electron transport when
163 a metallic filament bridges between two electrodes kept at different potentials. This originates

164 from the diffusive nature of Eq. (4) used to equilibrate the electrochemical potential. We note
165 that under diffusive electrical transport the gradient of the electrochemical potential is
166 proportional to the electronic current density; thus, the Laplacian in the RHS of Eq. (4)
167 represents the divergence of the current density around site i (i.e. time derivative of the total
168 charge density around the site). The details of the calculation of an electronic current are
169 explained in Ref.¹¹ and will not be repeated here in the interest of brevity. EChemDID has been
170 implemented in the parallel molecular dynamics package LAMMPS from Sandia National
171 Laboratories³⁵ and is available for download from our website.³⁶

172 **EChemDID summary.** In concluding this section, we point out that simulations presented here
173 involve no tunable parameters and are, thus, predictive. The inputs are force field parameters
174 that were obtained from ab initio simulations designed to describe the various interactions but
175 not specifically designed for electrochemistry or ECM simulations. The EChemDID parameters
176 to describe the equilibration of electrochemical potential have a negligible role in the
177 simulations are only chosen so that the equilibration of the voltage occurs fast compared with
178 atomic processes. We also highlight that simulations of this complexity necessarily involve
179 approximations, neglect processes and include uncertainties. These include the use of a force
180 field to describe atomic interactions, limitations intrinsic to the charge equilibration method
181 used, and the neglect of electronic transport when a conducting filament forms. As discussed in
182 Section 5 we believe these approximations do not affect the main results of our simulations.

183 As with all other simulation techniques EChemDID is not without approximations. In addition to
184 the use of an interatomic potential to describe interactions, EChemDID does not describe
185 electron transport (including trapping defects). Consequently, Joule heating and electron

186 migration are not modeled at this point. These processes would not play an important role until
187 a bridging filament is formed, enabling electronic current. However, a compliance current is
188 imposed to limit electron flow and control the conductivity of the filament;^{37,38} thus limiting
189 Joule heating. A characteristic time for thermal equilibration can be estimated as the ratio
190 between a characteristic length squared (taking into account the oxide thickness we can take
191 this as $\sim 4 \text{ nm}^2$) and the thermal diffusivity (a typical value for oxides is $10^{-6} \text{ m}^2/\text{s}$). This yields 4
192 ps, indicating that thermal equilibration occurs in timescales significantly shorter as compared
193 with switching and justify our neglect of Joule heating and the use of a thermostat to maintain
194 constant temperature throughout the simulations. The neglect of Joule heating in the current
195 version of EChemDID implies that RESET is governed by electrochemical dissolution and not
196 aided or driven by Joule heating. This is consistent with experimental observations in bi-polar
197 devices where erase voltages are lower than those required to significant Joule heating³⁹ but
198 would not apply to unipolar devices.³

199 2.3 DFT electronic structure calculations

200 Ab initio electronic structure calculations of the operation of the ECMs of interest here will be
201 computationally prohibitively expensive for the foreseeable future; yet, only such calculations
202 can provide answers to some of the key open questions in the field such as the nature of
203 electronic transport. To bridge this gap, we performed EChemDID MD simulations on small
204 simulation cells (275 atoms) and extracted a series of atomistic configurations to study their
205 electronic structure using density functional (DFT) calculations.

206 The geometry optimization and electronic structure calculations were carried out with DFT
207 using the Vienna *ab initio* simulation package (VASP)^{40,41}. Projector-augmented-wave (PAW)

208 pseudopotentials⁴² were used to describe core electrons, and the electron exchange-
209 correlation potential was computed within the generalized gradient approximation (GGA) as
210 proposed by *Perdew-Burke-ErnZerhof* (PBE)⁴³. The kinetic energy cutoff was set to 500 eV and
211 only gamma-point calculations were carried out due to the relatively large simulation cells. The
212 conjugate gradient method was used for the structural relaxation with a maximum force
213 tolerance of 0.01 eV/Å and the self-consistent field electronic relaxation proceeds until a
214 tolerance of 1×10^{-5} eV is reached.

215 3. ECM simulations: role of dielectric chemistry and structure on 216 switching

217 3.1 Systems of interest and simulation details

218 We study ECM cells with Cu as the active electrode and amorphous SiO₂ electrolytes; this
219 system is attractive due to the wide availability of experimental data and compatibility with
220 CMOS processing. In order to study the effect of device geometry on switching timescales and
221 filament stability, we focus on three classes of devices, see Figure 2: i) a parallel electrodes
222 setup with an active electrode patterned in a conical shape, as described in our previous
223 study,¹⁰ ii) a nanowire geometry with a shell made of the active electrode and an inactive
224 electrode core separated by the dielectric (center panels of Figure 2), and iii) a structure with a
225 fin shaped active electrode (right panels in Figure 2). We impose periodic boundary conditions
226 in two dimensions for the parallel electrodes and fin devices and 1D periodic boundary
227 conditions in the nanowires. For better statistics, we generated an ensemble of structures of
228 each type of devices differing only in the atomic structure of the amorphous dielectric; these

229 will be denoted C1-C4 (conical electrode), NW1-NW4 (core-shell nanowires) and F1-F4 (for the
230 fins). In order to isolate the effect of device geometry on switching timescales, the nanowire
231 and fin devices both have dielectric thicknesses of 1 nm; this is also the separation between the
232 tip of the cone and the inactive electrode in the parallel plates device. In this way, the distance
233 ions need to migrate to reach the inactive is nominally identical in all cases. For simplicity, the
234 inactive electrode is modeled using Cu interatomic potential but all atoms are kept at fixed
235 positions throughout the simulation.

236 The number of atoms in the devices range from 20,594 to 47,847 and the MD simulations of
237 switching involve up to 2.5 ns timescales. Such system sizes and timescales are beyond the
238 capabilities of ab initio simulations today and in the near future, highlighting the importance of
239 empirical approaches like EChemDID and reactive force fields. Even with EChemDID/ReaxFF, the
240 simulations presented here are computationally intensive; for example, a 1.5 nanosecond
241 simulation of the NW1 device takes 670 hours of wall clock time running on 32 cores of Purdue
242 University's Conte compute cluster.



243

244 *Figure 2. Geometry of the three types of ECM cells studied: parallel electrodes with patterned*
245 *active electrode, core/shell nanowires, and fin active electrodes. Top panels show relaxed*
246 *geometries and bottom show open representations of the structures.*

247

248 Generating well-relaxed amorphous structures for the dielectric is critical for the reliability and
249 reproducibility of the simulations. We start from an amorphous SiO_2 (a- SiO_2) system with
250 30,000 atoms generated following a melt and quench procedure as described in our previous
251 work.⁴⁵ The a- SiO_2 is then patterned in the desired shape and inserted between the active and
252 inactive electrodes. Additional Si and O atoms are added to the electrolyte in order to maintain
253 the overall stoichiometry of as SiO_2 . The dielectric is then re-annealed in the presence of the
254 electrodes; we heat the SiO_2 to $T=4000$ K and maintain this temperature for 50 ps while keeping

255 the atoms in the electrodes as a rigid body. We follow this high-temperature relaxation by an
256 annealing to $T=300$ K in 370 ps (cooling down at 10 K/ps). The last step in the preparation of the
257 cells for electrochemical switching is thermalization of the entire system (including electrodes)
258 at a temperature of 300 K. The final cells are stress free and the densities of the a-SiO₂ dielectric
259 are consistent with previous work and in good agreement with experiment.

260 All simulations are performed using the parallel MD simulator LAMMPS³⁵ with atomic
261 interactions described using ReaxFF as described in Ref.10. All simulations use the following
262 EChemDID parameters. The range of the weighting function that describes the equilibration of
263 the electrochemical potential is set to 4Å and the parameter k^ϕ that describes the fictitious
264 electrochemical diffusivity is 4 Å²/fs.

265 3.2 Reactive MD simulations of switching

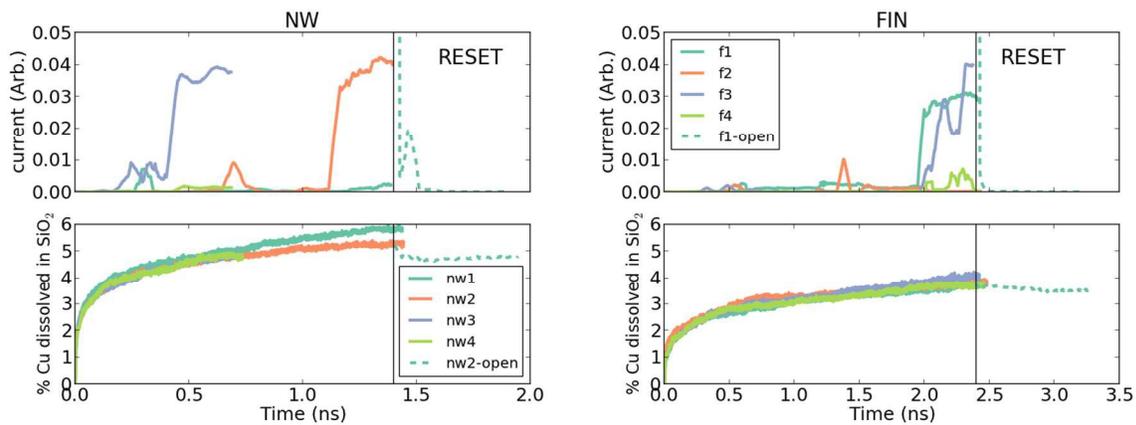
266 Before operation, i.e. the periodic switching of the device to the low-resistance state (SET) and
267 the high-resistance state (RESET) the devices need to be *FORMED*, i.e. switched for the first
268 time. This initial switching often requires higher voltages and longer times than the subsequent
269 SET processes. In order to simulate the FORMING of the devices described in Section 3.1 we
270 apply an electrochemical potential of 8 V across the cell, setting the electrochemical potential
271 of +4 V to the active electrode and -4 V to the inactive one. The electrochemical potential is
272 externally set for a metallic group of atoms away from the electrochemically active interfaces
273 and EChemDID equilibrates the potential across the two metallic electrodes, see Figure 1.

274 The top panels of Figure 3 show the EChemDID current (see Eq. 10 in Ref. 11) between the
275 electrodes as a function of time during the FORM simulations. A non-zero value indicates the

276 presence of the bridging metallic filament between the active and inactive electrode. The
277 results are consistent with our previous simulations on parallel electrode setups with patterned
278 active electrodes.¹¹ These simulations showed switching timescales ranging from approximately
279 0.5 ns to 5 ns and intermittent switching in many cases caused by metastable single-atomic
280 chain filaments. These switching timescales are consistent with experimental results⁵; we
281 consider this agreement quite remarkable given that none of the model parameters were
282 tuned to describe neither ECM cells nor electrochemical reactions.

283 Interestingly, the simulations reported in Figure 3 show that the nanowire devices tend to
284 switch at shorter times than the FIN ones. Devices NW3 and NW2 switch within ~ 0.5 and ~ 1.2
285 ns of the application of the voltage while no FIN device switches before 1.7 ns. Devices NW4
286 and NW1 exhibit intermittent switching before 1.5 ns (denoted by a weak and fluctuating
287 current). We found that the NWs switching timescales are consistent with the geometries
288 studied in Ref. [10] composed of conical and triangular patterned active electrodes. As the Cu
289 ions dissolve into the dielectric and move towards the inactive electrode core, their density
290 increases and so does the chance of forming nanoscale Cu clusters that are critical for
291 switching. Figure 3 (bottom panels) shows the time evolution of the density of Cu atoms
292 dissolved in the dielectric. The density of Cu ions in the dielectric increases faster in the NW
293 devices. The EChemDID currents and Cu concentration in Figure 3 indicate that reaching a
294 threshold density of Cu dissolved in the dielectric is a necessary condition for stable switching
295 but it is not sufficient. Consistent with Ref. [10], our results indicate that stable switching
296 requires at least 4% Cu per SiO₂ atoms but that this alone does not guarantee stable switching.
297 We attribute the slower switching timescales of the FIN devices to the large fraction of their

298 electrode/dielectric interface being atomically flat (perfectly flat interfaces tend to slow the
 299 copper dissolution and therefore increase switching time, as will be discussed in Section 4). In
 300 addition, the nanowire geometry leads to a convergence of the dissolved ions into smaller areas
 301 as they approach the inactive core electrode favoring the formation of Cu clusters and a
 302 conductive filament.



303
 304 *Figure 3. Electrical current computed with EChemDID (top) for nanowire (left) and fin shaped*
 305 *(right) structures as well as the corresponding concentration of Cu dissolved in the solid*
 306 *electrolyte (bottom).*

307 Following the FORMING simulations, we RESET one device of each geometry (NW2 and F1) by
 308 reversing the voltage. The results are shown as dotted lines in Figure 3. When the voltage is
 309 reversed, a large amount of current is detected because the electrochemical potential has to be
 310 re-equilibrated in both electrodes, hence the peaks at 1.5 ns and 2.5 ns observed for the NW2
 311 and F1 structures, respectively. Device F1 switches OFF in a short period of time (in
 312 approximately 10 ps) whereas it takes an order of magnitude longer time to switch OFF the NW
 313 device (~100 ps). This last observation correlates with the high concentration of Cu dissolved in

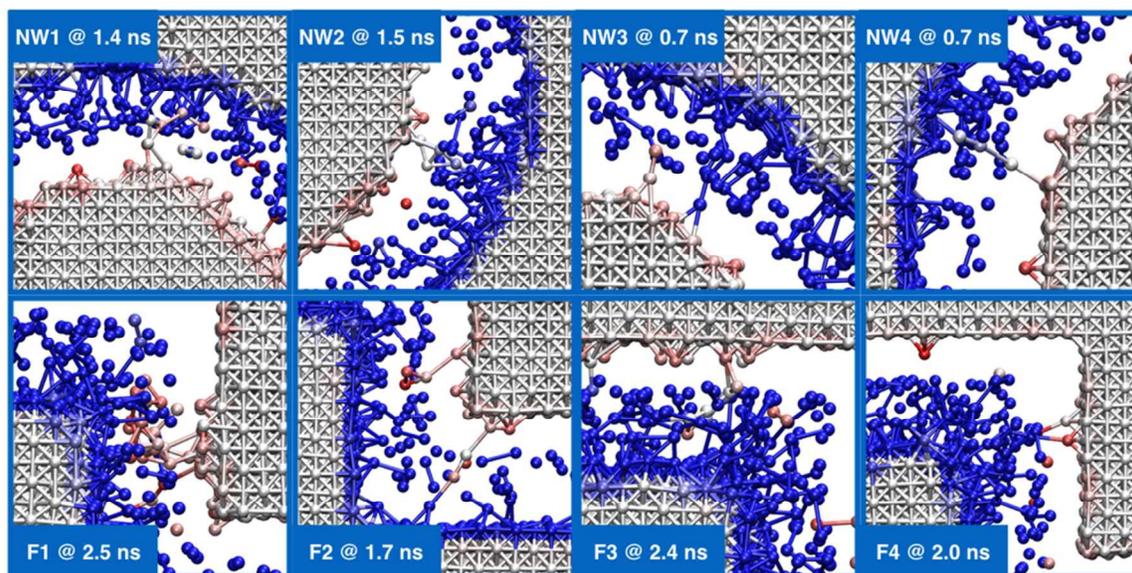
314 the electrolyte for the NW case, slowing down the RESET process. As with FORMING, we expect
315 significant device-to-device variability and study involving several structures and multiple
316 SET/RESET cycles will be required to draw more rigorous conclusions.

317 3.3 Atomic structure of bridging filaments and dielectric structure

318 We now focus on the atomistic structure of the nanoscale filaments responsible for the low-
319 resistance state of the devices and the effect of the metallic ions have on the amorphous
320 dielectrics. Knowledge of the shape of the bridging filament is important to predict its electrical
321 characteristics and can provide insight into the process of their formation as well as stability.
322 Similarly important is to understand the processes that occur in the dielectric as it
323 accommodates the ions during switching. For example, it has been postulated that nanoscale
324 voids or cavities created during the FORMING process contribute to subsequent switching
325 steps⁴⁴.

326 Figure 4 shows snapshots of the bridging filaments of the various devices. For clarity only
327 metallic atoms are shown and they are colored according to their partial charges (blue
328 represents positive charge and red negative). The snapshots clearly show the positive charge of
329 the metallic atoms on the surface of the active electrode and ions dissolved into the dielectric.
330 In addition, inspection of atoms that have come into contact with the inactive electrode reveals
331 their electrochemical reduction as described by EChemDID. This chemical reduction stabilizes
332 the atoms in contact with the negative electrode (electro-positive ions in contact with the
333 active electrode are favored to dissolve into the dielectric while dissolution is unfavorable for
334 neutral or negatively charged Cu atoms). As we found for planar geometries, stable switching
335 requires filaments a few atoms thick near the active (positive) electrode but chemical reduction

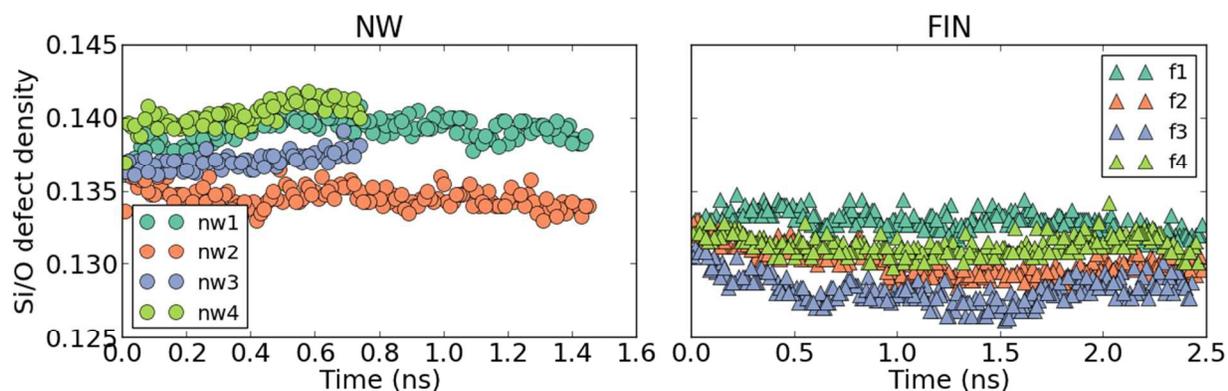
336 enables thinner (even single atom) shapes near the inactive electrode. This leads to filaments
337 with approximately conical shapes, thicker near the active electrode. We stress that this shape
338 has its origin in the relative stability of Cu near either electrode and not in the growth process.



339
340 *Figure 4. Snapshots of the metallic filaments observed in the simulations. The top and bottom*
341 *snapshots show filaments observed in NWs and FIN geometries, respectively. The colors*
342 *represent partial atomic charges ranging from $-0.2e$ (red) to $+0.2e$ (blue) and the amorphous*
343 *silica has been hidden for clarity.*

344 We now turn our attention to the atomistic structure of the dielectric during switching.
345 Specifically, we focus on possible defects generated as Cu ions migrate through the amorphous
346 structure. A perfect amorphous SiO_2 network consists of SiO_4 tetrahedra bridged by shared O
347 atoms and deviations from this coordination indicate point defects. Thus, we characterize the
348 local coordination of each Si and O atom in the dielectrics during switching and identify defects
349 as sites that deviate from the perfect network (i.e. Si with coordination other than four O atoms
350 and O atoms with coordination other than two Si). Figure 5 shows the temporal evolution of the

351 fraction of defective atoms in the simulations. As in all amorphous structures a level of intrinsic
 352 defects is present from the outset.⁴⁵ The small device to device variability denotes the
 353 reproducibility of the structure generation procedure and that of the simulation results in
 354 general. Quite surprisingly, the density of defects does not increase during the FORMING
 355 process, the amorphous structure is able to accommodate the electrochemically dissolved
 356 metallic ions. This is an important result and it indicates that the process of FORMING does not
 357 generate permanent defects or channels that could subsequently be used for switching during
 358 SET and RESET. In addition, this result indicates that structural changes or defects in the
 359 dielectric are not likely to contribute to the electronic transport. This observation applies to the
 360 nanoscale devices studied here and it is possible that nanoscale pores or channels form in
 361 larger devices.



362
 363 *Figure 5. Total point defect density (Silicon and Oxygen) in the α -SiO₂ electrolyte for various ECM*
 364 *cells (left: NWs and right: FIN geometries) as a function of switching time.*

365 4. Multiscale modeling of electronic structure during switching

366 4.1 Systems of interest and simulation details

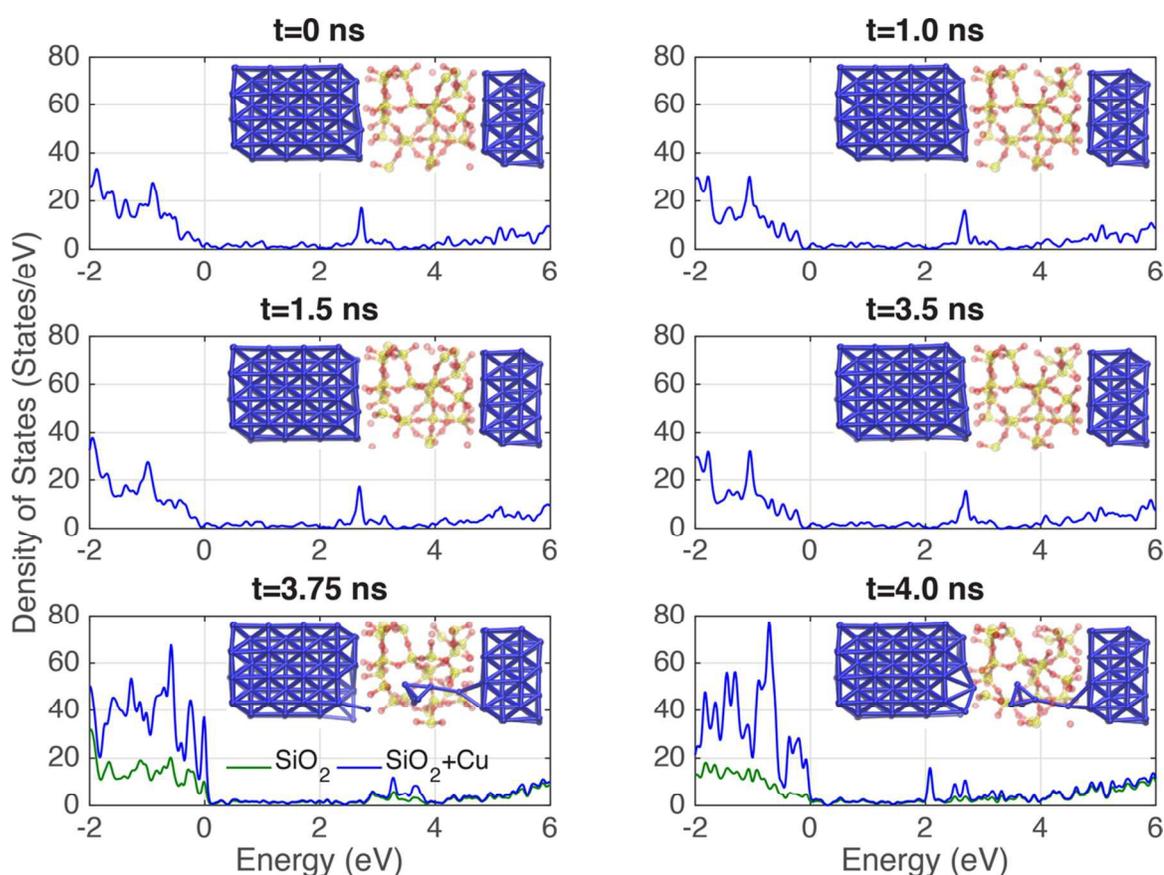
367 In order to characterize the electronic structure of the electrochemical metallization cells
368 during switching we performed DFT calculations of atomic configurations obtained during the
369 switching of a small device as described in Section 2.3. The device, see snapshots in Figure 6
370 consists of parallel, flat electrodes and a 1.3 nm thick dielectric. The cross-sectional area of the
371 simulation cell is 1.05 x 1.05 nm. The generation of the atomistic structure of the smaller
372 devices only differs from the one laid down in Section 3.1 in the selection of electrodes
373 termination and switching voltage. Due to the limited number of atoms, we use atomistically
374 flat terminations for the electrochemically active and inactive electrodes which makes the
375 initial dissolution of ions into the dielectric more difficult. As in Section 3, the switching process
376 is driven by a potential difference of 8 V across the device.

377 The total MD simulation time of the small device is 8.25 ns, and copper ions dissolution is
378 initially observed to take place around 3.5 ns. The insets in Figure 6 show the atomic snapshots
379 of the metal-insulator-metal device at different stages of the switching process and these select
380 structures are used for the DFT calculations. The MD generated structures are fully relaxed with
381 DFT-GGA using the settings and tolerances discussed in Section 2.3. The electronic density of
382 states (Kohn-Sham eigenvalues) of the relaxed structure is calculated and projected on the
383 atomic sites of the dielectric region to study how the addition of Cu ions changes its electronic
384 structure.

385 4.2 Electronic structure evolution during switching

386 Figure 6 shows the electronic density of states of the dielectric region (amorphous silicon
387 dioxide and dissolved Cu ions) at several stages of the switching process. We observe a
388 relatively small availability of states in the vicinity of the Fermi level (located at zero in all cases)
389 during the first 3.5 ns of the simulation when no copper ions have been dissolved. In these
390 plots, the valence band edge is right below zero and the conduction band starts at near 4eV. As
391 expected, intrinsic defects lead to electronic states within the band gap and we attribute the
392 slight variation in the density of states before any copper is embedded in the electrolyte to
393 variations in the amorphous structure.⁴⁶ A detailed analysis of the electronic structure of the
394 initial amorphous SiO₂ including the effect of defects and surface states is beyond the scope of
395 this paper where we focus on the effects on the dissolution of Cu. The dissolution of the first
396 ion takes place at approximately 3.7 ns and this is followed by the rapid dissolution of several
397 nearby ions and the formation of an ultra-thin filament, see snapshots at 3.75 and 4.0 ns. The
398 presence of these metallic ions leads to a sharp increase in the density of states of the dielectric
399 region around the Fermi energy. Further analysis of the density of states via a projection on Si
400 and O atoms (shown as green lines in the bottom panels of Fig. 6) indicates that their
401 contribution to the states around the Fermi energy is minimal. Thus, the electronic states
402 responsible for electronic transport are contributed by the metallic ions and not by defects
403 induced in the dielectric. This is in agreement with other DFT calculations⁴⁷ on crystalline silicon
404 dioxide with copper inclusions where copper derived states show a dominant contribution to
405 the top of the valence band and bottom of the conduction band. Pandey *et. al.* reports an
406 increase in the number of localized states in the mid-gap with increasing concentration of

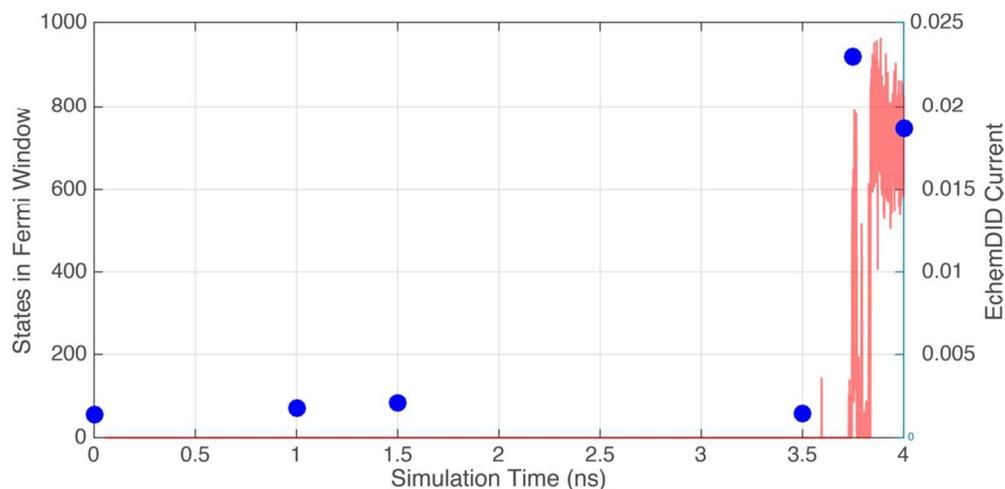
407 copper and complete metallization for concentrations greater than $3.3 \times 10^{22} \text{cm}^{-3}$. Our
 408 simulations at 4 ns have a Cu concentration of $2.0 \times 10^{22} \text{cm}^{-3}$. It is also worth noting that the
 409 geometric shape of the copper clusters in the amorphous silicon dioxide is consistent with
 410 previous MD/DFT studies⁴⁸ where it is suggested that the most stable clusters adopt an
 411 equiaxed geometry, as observed for the copper tetramer shown in the inset of Figure 6 at $t=4.0$
 412 ns.



413
 414 *Figure 6. Projected density of states for small electrochemical metallization cell devices*
 415 *and snapshots of the atomic structure throughout the switching process. The density of states*
 416 *has been projected on the atoms of the solid electrolyte region*

417

418 Figure 7 provides a measure of the change in electronic conductance of device during
419 switching, we show the density of states integrated in a Fermi window of ± 0.2 eV as function
420 of simulation time. As described above, there is a sudden increase in the number of states
421 around the Fermi level when copper ions are embedded in the silicon dioxide. The DFT
422 calculation (blue circles) is compared with EChemDID electronic current obtained from Eq. 4.
423 Both methods show very similar trends lending credence to the EChemDID current calculation
424 as an accurate estimator. We note that these simulation cells are smaller than those described
425 in Section 3, which would result in quantum confinement and other size effects that affect the
426 predictions.



427
428 *Figure 7. Integrated density of states in a Fermi window of ± 0.2 eV. The variation of the*
429 *number of states in the early stages of the simulation is associated to the continuously changing*
430 *atomic structure of the amorphous silicon dioxide. The sudden increase in states available for*
431 *conduction is attributed to the inclusion of copper ions in the solid electrolyte.*

432 5. Conclusions and outlook

433 In summary this paper describes EChemDID, a model to perform large-scale reactive atomistic
434 simulations of electrochemical processes, and its application to simulate resistive switching in
435 nanoscale ECMs. MD simulations provide unparalleled resolution for devices at their scalability
436 limit (nanometer dimensions) and at ultra-fast switching conditions of interest in many
437 applications. The simulations, with no adjustable parameters, predict switching in nanosecond
438 timescales and significant device to device variability, this is consistent with experimental
439 observations. The simulations indicate that nanowire devices consisting of active electrode
440 shells and where ions move in a convergent geometry towards the inactive electrode core
441 switch at shorter timescale than those involving parallel electrodes. Given the significant device
442 to device variability a larger number of simulations would be required to assess the distribution
443 of performance (e.g. switching timescales, filaments stability) of the various devices. The
444 simulations confirm that a threshold density of dissolved ions is necessary for switching (in the
445 case of Cu/SiO₂ systems this value is 4% Cu per silica formula unit); but this condition is not
446 sufficient. The formation of a stable filament required the formation of small Cu clusters that
447 help the stability especially near the active electrode. Electrochemical reduction stabilizes thin
448 filaments near the inactive electrode leading to filaments thinner near the negative electrode.

449 A detailed characterization of the atomic structure of the dielectric during switching shows no
450 indication of the disruption of the amorphous network during the dissolution of the ions and
451 the formation of a nanoscale conductive bridge. The amorphous network accommodates the
452 ions with little distortions and this is confirmed by electronic structure calculations using

453 density functional theory that shows that during switching the electronic states near the Fermi
454 energy responsible to conductance are predominantly associated with the Cu ions.

455 We stress that no model parameter was adjusted to describe ECMs or even electrochemistry; in
456 that sense the models described in this paper are predictive. Of course, the simulations make
457 several approximations that need to be taken into account when interpreting the results. The
458 ReaxFF force field (as any other method to compute energies and interatomic forces, including
459 most ab initio ones) provides an approximate description of the interactions. For example, the
460 potential we use slightly underestimates the dissolution energy of Cu into SiO₂; the
461 uncertainties introduced in the simulations due this effect have been discussed in detail in Ref.
462 [10]. The atomic-based charge equilibration method used here has limitations that have been
463 documented in recent papers^{49,50}. Importantly for our specific application is that we neglect
464 integer charge transfer processes (a dissolved ion or defect in the dielectric trapping a hole or
465 electron); we consider the Cu ions to carry an *average* charge as they migrate through the
466 dielectric. Müser and collaborators recently proposed an approach to capture such processes⁵¹
467 and used to simulate a model battery.⁵² Combining this approach with EChemDID would be
468 worthwhile and its parameterization could be performed from first principles calculations.⁴⁶

469 Our simulations also neglect electric transport when a filament forms. Performing a detailed
470 calculation of the possible Joule heating and electromigration on the nanoscale filaments
471 predicted by EChemDID, accounting for possible ballistic effects on electron transport, would
472 provide significant insight into their role in switching. This is particularly important to
473 understand the dissolution of the filament during the RESET process and the current is
474 externally limited during filament formation.

475 Finally we point out that EChemDID is quite generally applicable and could be used in
476 conjunction with reactive force fields to simulate a wide range of devices including pseudo
477 capacitors and batteries in addition to ECMs.

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